ADVANCED CMOS TECHNOLOGY 2020
(The 7/5 nm Nodes)
October 28, 29, 30, 2020; An ONLINE Course

1. Detailed step-by-step 7 nm FinFET fabrication process (front-end & back-end)
2. FinFET manufacturing issues and solutions
3. Horizontal Nanoshhet fabrication process flow
4. DRAM Memory Fabrication and Yield Issues
5. Detailed 3D Flash fabrication process flow and manufacturing issues
6. Future memory technologies
7. Extensive SEM/TEM Survey of Leading-edge devices
8. EUV Applications, Power Solutions and Status Update
9. 3D Packaging Versus 3D Monolithic packaging status update
10. CMOS Technology Forecast: 5 nm, 3 nm, 2 nm, 1 nm nodes

COVERED ARE 7NM FINFET, 3D FLASH AND 3NM NANOWIRE FABRICATION DETAILS

COURSE CONTENT IS UPDATED & TECHNICALLY CURRENT THROUGH OCTOBER 2020

Threshold Systems
www.ThresholdSystems.com
**Advanced CMOS Technology - An Online Course**

**THE 7/5 NM NODES**

This is the best and the most important course that you can attend this year to learn about the key technical breakthroughs in Logic and Memory that have enabled 7 nm node technology, and the manufacturing challenges of 3D Flash, 7 nm FinFETs and 5 nm Nanosheets.

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**Course Contents**

1. **Process integration.** The 7 nm technology nodes represent landmarks in semiconductor manufacturing.
   - The enduring myth of a technology node
   - Market forces: the shift to mobile applications
   - The Idsat equation
   - Ion/loff curves, scaling methodology

2. **Detailed 7 nm FinFET Fabrication Sequence.** The FinFet represents a radical departure in transistor architecture.
   - A detailed step-by-step 7 nm FinFET fabrication process
   - FinFET High-k/Metal Gate integration
   - Cobalt contacts and Cobalt metal lines
   - Details of Back-End metallization methodologies and air-gap dielectrics

3. **Nanosheet Fabrication.**
   - The drive to Gate-All-Around (GAA) devices
   - Nanowire SCE control and scaling
   - A detailed 3nm Nanosheet fabrication process
   - Key fabrication details and manufacturing problems
   - Vertical versus horizontal Nanowires: advantages and disadvantages

4. **Planar Flash & DRAM Memory.**
   - DRAM memory function and nomenclature
   - DRAM scaling limits
   - Planar Flash operation and function
   - Planar Flash scaling techniques

5. **3D Flash Memory.**
   - A detailed step-by-step Samsung 3D NAND Flash fabrication process
   - Staircase fabrication methodology
   - The role of ALD in 3D Flash fabrication
   - The Intel-Micron 3D NAND process

6. **Advanced Lithography.**
   - Physical Limits of Lithography Tools
   - Immersion Lithography - principles and practice
   - Double, and Quadruple patterning
   - EUV Lithography: status, problems and solutions
   - Resolution Enhancement Technologies

7. **Emerging Memory Technologies.**
   - Cross-point memory
   - Phase Change Memory (PCRAM)
   - Resistive RAM (ReRAM)
   - Spin Torque Transfer RAM (STT-RAM) – the brightest prospect?

8. **Survey of leading edge devices.** This part of the course presents a visual feast of TEMs and SEMs of real-world, leading edge devices for Logic, DRAM, and Flash memory. It is presented by Dick James, the Fellow Emeritus of TechInsights.

9. **3D Packaging versus Monolithic 3D - which way to go?**
   - TSV technology: design, processing and production
   - Interposers: the shortcut to 3D packaging
   - Monolithic 3D fabrication processes
   - Annealing 3D Monolithic structures
   - The Internet of Things (IoT).

10. **The Way forward: a CMOS technology forecast.**
    - The transition to 3D devices (Logic & Flash Memory)
    - The Future of Memory and Logic
    - New nanoscale effects and their impact on future CMOS device architecture and materials
    - Is Moore's law finally coming to an end?
How Online Learning Works:

Shortly after registration you will be emailed a link that will take you to the online classroom the day of the course. The week before the class begins a binder of color course notes will be shipped to you via Fedex or UPS.

The class is three days long and will begin on October 28, 2020 at 9:00 PDT. On that day you simply click on the link that has been provided and you will be seamlessly taken to the online classroom where you will be able to see, hear and interact with the instructor.

Who Should Attend:

- Equipment Suppliers & Metrology Engineers
- Fabless Design Engineers and Managers
- Foundry Interface Engineers and Managers
- Device and Process Engineers
- Design Engineers

- Product Engineers
- Process Development & Process Integration Engineers
- Process Equipment & Marketing Managers
- Materials Suppliers & Applications Engineers
- Patent Attorneys

Course Instructors:

The best instructors in the business teach this course. All of the instructors are world-class experts in their fields, with decades of industry experience. However, these presenters have been selected not just for their deep technical expertise, but also for their ability to present complex technical information in a clear and engaging manner. Each of these instructors is an experienced and skilled public speaker, and the accompanying course notes for this seminar are profusely illustrated with high-quality 3D color graphics and relevant SEMs and TEMs. We want you to leave this course with a clear understanding of the key enabling technologies that have made the 10/7 nm node technologies a reality, as well as an understanding of what the central technical challenges are for the 5 nm node. After you have completed this course you will never again leave a meeting wondering what people were talking about.

Jerry Healey has been a technical professional in the semiconductor industry for 30 years, 8 years of which were spent as a Device Engineer at Motorola Semiconductor. He was formerly an instructor for UC Berkeley Extension (College of Engineering), and was also employed as a Process Integration Engineer at both Sematech and the Advanced Technology Development Facility (ATDF), where he worked on advanced technology node development. He is a renowned lecturer in the field of silicon processing, and his areas of expertise include process integration, technology transfer of new processes from R&D into manufacturing, Nanosheet and FinFET fabrication. His audiences remember him for the breadth of his knowledge regarding semiconductor manufacturing, his engaging lecture style, and the insightful color graphics he uses to illustrate his lectures.

Dr. Moshe Preil is a world-class lithographer with over 30 years of experience in the field. He has worked at AMD, Luminescent, ASML and most recently he was the Manager of Emerging Lithography Technology at Global Foundries. Currently he is the Senior Marketing Manager in the Patterning Division at KLA-Tencor. He has lead teams tasked with investigating state-of-the-art Lithography tools and processes such as Directed Self Assembly (DSA) and e-Beam Direct Write (EBDW) as well as managed an EUV lithography tool. A dramatic and engaging public speaker, Dr. Preil has taught numerous courses on the subject of optical lithography, has published extensively in this field, and is widely regarded as a gifted and inspiring instructor.

Dick James is the Fellow Emeritus for TechInsights, an Ottawa, Canada-based reverse engineering company that specializes in semiconductors and electronic systems. Dick joined TechInsights predecessor, Chipworks, in 1995 and acts as a consultant to TechInsights’ staff and customers, dealing with the microstructural characterization of devices, both process and packaging. He is also a much sought-after speaker at technical conferences and a popular blogger at TechInsights.com and ElectroIQ.com, and other publications.

Dick James has over 40 years’ experience in process development, design, manufacturing, packaging and reverse engineering of semiconductor devices and is a world authority on the interpretation and analysis of Scanning and Transmission Electron Micrographs.

Tuition: $1,795

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